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(54) Title: Method for Producing Parts and a Vacuum Processing System

(57) Abstract: When producing coated parts, the same demands for coating parts are made as those for effecting a coating with an epitaxial layer. According to the invention, a reactive gas is admitted into a process chamber (PR) and is activated by means of a low-energy plasma discharge. In order to improve the industrial capability of a method of the aforementioned type, the process chamber (PR) is separated (14) from the inner wall of the recipient (1) located in the surrounding area.